IFW IFW

03500.014179.

PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

n re Application of:		)	Examiner: M. Santiago
YOICHI ANDO ET AL.		)	Exammer, M. Santiago
Application No.: 09/722,454		:	Group Art Unit: 2879
Appn	Cation No.: 03/122,434	) :	
Filed: November 28, 2000		)	
For:	METHOD FOR MANUFACTURING ELECTRON BEAM DEVICE, METHOD FOR MANUFACTURING IMAGE FORMING APPARATUS, ELECTRON BEAM DEVICE AND IMAGE FORMING APPARATUS MANUFACTURED THOSE	· ) : ) : )	
	MANUFACTURING METHODS, METHOD AND APPARATUS FOR MANUFACTURING ELECTRON	: ) :	
	SOURCE, AND APPARATUS FOR MANUFACTURING IMAGE FORMING APPARATUS	)	May 13, 2004
		,	

Mail Stop Issue Fee Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## LETTER TRANSMITTING CORRECTED DRAWINGS

Sir:

Transmitted herewith are nine (9) sheets of formal drawings to be substituted for the corresponding drawing sheets presently on file in the above-identified application.

The new drawing sheets formalize and incorporate the changes made in the Request for Approval To Make Drawing Changes dated February 9, 2004.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,

Registration No.

FITZPATRICK, CELLA, HARPER & SCINTO

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